



Information and Control Global Technical Committee

Japan TC Chapter

Meeting Summary and Minutes

Japan Standards Spring 2019 Meetings

April 17, 2019 Begin 13:30 – End 17:30

SEMI Japan, Tokyo, Japan

TC Chapter Announcements

Next TC Chapter Meeting

Thursday, July 25, 2019, Begin 13:00 – End 17:00

SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Italics indicate virtual participants

Co-Chairs: Takayuki Nishimura (SCREEN Semiconductor Solutions), Mitsuhiro Matsuda (KOKUSAI ELECTRIC)

SEMI Staff: Mizue Iwamura

<i>Company</i>	<i>First</i>	<i>Last</i>	<i>Company</i>	<i>First</i>	<i>Last</i>
KEYENCE	Hirokazu	Tsunobuchi	Tokyo Electron	Tadashi	Mochizuki
Hitachi High-Technologies	Yuko	Toyoshima	Tokyo Electron	Masaya	Nagata
Hitachi High-Technologies	Takuma	Yamaki	Yokogawa Solution Service	Takashi	Nakagawa
IBM Japan Services	Osamu	Ohishi	ZAMA Consulting	Mitsune	Sakamoto
KOKUSAI ELECTRIC	Mitsuhiro	Matsuda			
SCREEN Semiconductor Solutions	Takayuki	Nishimura			
Tokyo Electron	Naoko	Murata	SEMI Japan	Mizue	Iwamura

Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
None.		

Table 3 Committee Structure Changes

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>
None.	

Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
6377A	Line Item revision to SEMI E5-1217: Specification for SEMI Equipment Communications Standard 2 Message Content (SECS-II)	
Line Item 1	Make the following revisions to SECS message definitions in SEMI E5 to be compatible with the changes being done parallelly by #R6375 and former #6375 Major Revision to SEMI E170-1217 and E170.1-1217.	Failed , Returned to TF for rework
6481	Line Item Revision to SEMI E174-0618: Specification for Wafer Job Management (WJM)	
Line Item 1	Eliminate PEMFlag in response to the deletion of PEMFlag from E170 SFORMS	Failed , Returned to TF for rework
Line Item 2	Replace Figure 1 Wafer Job (WJ) and Wafer Job Management Job (WJMJ) for better understanding	Passed , as balloted
6300B	New Standard: Guide for EDA Freeze Version	Failed , Returned to TF for rework

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Activities Approved by the GCS between meetings of the TC Chapter

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None.			

Table 6 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

#	Type	SC/TF/WG	Details
None.			

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOF>

Table 7 Authorized Ballots

#	When	TF	Details
6377B	Cycle5 or 6-2019	GEM 300 TF	Line Item revision to SEMI E5-1217: SEMI EQUIPMENT COMMUNICATIONS STANDARD 2 MESSAGE CONTENT (SECS-II)
6481A	Cycle5 or 6-2019	GEM300 TF	Line Item Revision to SEMI E174-0618: SPECIFICATION FOR WAFER JOB MANAGEMENT (WJM)
6300C	Cycle5-2019	DDA TF	New Standard: Guide for EDA Freeze Version

Table 8 SNARF(s) Granted a One-Year Extension

#	TF	Title	Expiration Date
None.			

Table 9 SNARF(s) Abolished

#	TF	Title
None.		

Table 10 Standard(s) to receive Inactive Status

Standard Designation	Title
None.	



Table 11 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
None.		

Table 12 Previous Meeting Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
None.		



1 Welcome, Reminders, and Introductions

Takayuki Nishimura (SCREEN Semiconductor Solutions) called the meeting to order at 13:30. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01-02_SEMI Standards Required Elements_August2018_E+J

2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

Motion: To approve the minutes of the previous meeting with as written.

By / 2nd: Mitsuhiro Matsuda (KOKUSAI ELECTRIC) / Masaya Nagata (Tokyo Electron)

Discussion: None.

Vote: 9-0, Motion Passed.

Attachment:

3 Liaison Reports

3.1 *Information & Control Europe TC Chapter*

None.

3.2 *Information & Control Korea TC Chapter*

Mitsuhiro Matsuda (KOKUSAI ELECTRIC) gave the Liaison Report as attached.

Attachment: 03-02_IC_KR_Liaison_April2019_v2

3.3 *Information & Control North America TC Chapter*

Mitsuhiro Matsuda (KOKUSAI ELECTRIC) gave the Liaison Report as attached.

Attachment: 03-03_NA IC Liaison Report Apr 2019_v2

3.4 *Information & Control Taiwan TC Chapter*

Mitsuhiro Matsuda (KOKUSAI ELECTRIC) gave the Liaison Report as attached.

Attachment: 03-04_20190329_TW_I&C TC Liaison Report v1

3.5 *CAST (Collaborative Alliance for Semiconductor Test)*

Mizue Iwamura (SEMI Japan) gave the CAST (Collaborative Alliance for Semiconductor Test) Report as attached.

Attachment: 03-05_SEMI CAST Overview 2019Apr25_Standards



3.6 North America Automated Test Equipment

Mizue Iwamura (SEMI Japan) gave the North America Automated Test Equipment Report as attached.

Attachment: 03-06_NA Liaison Report - ATE April 2019_v1

3.7 Staff Report

Mizue Iwamura (SEMI Japan) gave the SEMI Staff Report as attached.

Attachment: 03-07_SEMI Staff Report 2019_0409_v1

4 Ballot Review

NOTE 1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

4.1 Document #6300B, New Standard: Guide for EDA Freeze Version

4.1.1 The ballot failed and 6300C will be submitted in Cycle 5-2019.

Attachment: 04-01_6300B_Ballot report template with Technical ChangeRev1.2_r4

4.2 Document #6377A, Line Item revision to SEMI E5-1217: Specification for SEMI Equipment Communications Standard 2 Message Content (SECS-II)

4.2.1 Line Item 1: Make the following revisions to SECS message definitions in SEMI E5 to be compatible with the changes being done parallelly by #R6375 and former #6375 Major Revision to SEMI E170-1217 and E170.1-1217.

4.2.1.1 The ballot failed and 6377B will be submitted in Cycle 5 or 6-2019.

Attachment: 04-02_6377A_Ballot report (Line Item) with Technical ChangeRev1.5_r4

4.3 Document #6481, Line Item Revision to SEMI E174-0618: Specification for Wafer Job Management (WJM)

4.3.1 Line Item 1: Eliminate PEMFlag in response to the deletion of PEMFlag from E170 SFORMS

4.3.1.1 Line Item 1 failed and 6481A will be submitted in Cycle 5 or 6-2019.

4.3.2 Line Item 2: Replace Figure 1 Wafer Job (WJ) and Wafer Job Management Job (WJM) for better understanding

4.3.2.1 Line Item 2 **passed** TC Chapter review as balloted and will be submitted to the ISC A&R for procedural review.

Attachment: 04-03_6481_Ballot report template (Line Item) with Technical ChangeRev1.5_r4

5 Subcommittee and Task Force Reports

5.1 GEM300 TF

Masaya Nagata (Tokyo Electron) reported for the GEM 300 Task Force as attached.

Attachment: 05-01_JA_ICC_GEM300_TF_Report_2019_0417_R1.1

5.2 Japan I&C Maintenance TF

Mitsuhiro Matsuda (KOKUSAI ELECTRIC) reported that there are no activities currently working on.

5.3 Sensor Bus TF

None.

5.4 Diagnostic Data Acquisition (DDA) TF

Mitsune Sakamoto (Zama Consulting) reported for the DDA Task Force as attached.

Attachment: 05-04_DDATF_Japan_20190417-Report_To_ICC

5.5 Fab & Equipment Information Security Task Force

Tadashi Mochizuki (Tokyo Electron) reported for the Fab & Equipment Information Security Task Force as attached.

Attachment: 05-05_SEMI Stds JA FEIS TF Report_20190417

5.6 Equipment Data Acquisition (EDA) Working Group

Mitsune Sakamoto (Zama Consulting) reported that there are no activities currently working on.

5.7 Backend Factory Integration Task Force

None.

6 Old Business

6.1 Project Period Check

Mizue Iwamura (SEMI Japan) addressed that there is one documents that exceed by 2019.

6092: New Standard: Specification for Centralized User Authentication and Role Authorization Management (CUARAM) was approved by Information & Control Japan TC Chapter on October 20, 2016.

6.2 5 Year Review Check

6.2.1 E98.1-1102 Provisional Specification for SECS-II Protocol for the Object Based Equipment Model

Hideaki Ogihara (NaigaiTEC) to consider about this at next I&C Japan TC Chapter meeting.

7 New Business

7.1 Equipment and Materials Traceability TF and Single Device Traceability TF under Traceability TC

Hirokazu Tsunobuchi (KEYENCE) explained outlines of Equipment and Materials Traceability TF and Single Device Traceability TF under Traceability TC. Also, Hirokazu Tsunobuchi (KEYENCE) encouraged to participate those liaison TFs in Japan.

Attachment: 07-01_20190417TraceabilityTC

7.1 Ballot submission of 6377B: Line Item revision to SEMI E5-1217: SEMI EQUIPMENT COMMUNICATIONS STANDARD 2 MESSAGE CONTENT (SECS-II)

Osamu Ohishi (IBM Japan Services) addressed to the committee on this topic.

Motion: To approve a ballot submission of 6377B: Line Item revision to SEMI E5-1217: SEMI EQUIPMENT COMMUNICATIONS STANDARD 2 MESSAGE CONTENT (SECS-II) for Cycle 5 or 6, 2019

By / 2nd: Osamu Ohishi (IBM Japan Services) / Masaya Nagata (Tokyo Electron)

Discussion: None.

Vote: 10-0, Motion Passed.

7.2 Ballot submission of 6481A: Line Item Revision to SEMI E174-0618: SPECIFICATION FOR WAFER JOB MANAGEMENT (WJM)

Osamu Ohishi (IBM Japan Services) addressed to the committee on this topic.

Motion: To approve a ballot submission of 6481A: Line Item Revision to SEMI E174-0618: SPECIFICATION FOR WAFER JOB MANAGEMENT (WJM) for Cycle 5 or 6, 2019

By / 2nd: Osamu Ohishi (IBM Japan Services) / Masaya Nagata (Tokyo Electron)

Discussion: None.

Vote: 10-0, Motion Passed.

7.3 Ballot submission of 6300C: New Standard for Cycle 5, 2019

Mitsune Sakamoto (ZAMA Consulting) addressed to the committee on this topic.

Motion: To approve a ballot submission of 6300C: New Standard for Cycle 5, 2019

By / 2nd: Mitsune Sakamoto (ZAMA Consulting) / Takashi Nakagawa (Yokogawa Solution Service)

Discussion: None.

Vote: 10-0, Motion Passed.

8 Next Meeting and Adjournment

The next meeting is scheduled for 13:00-17:00 on Thursday, July 25, 2019 at SEMI Japan, Tokyo, Japan. See <http://www.semi.org/standards-events> for the current list of events.

Adjournment: 17:00.

Respectfully submitted by:



Mizue Iwamura

Coordinator

SEMI Japan

Phone: +81.3.3222.5760

Email: miwamura@semi.org

Minutes tentatively approved by:

Takayuki Nishimura (SCREEN Semiconductor Solutions), Co-chair	July 23, 2019
Mitsuhiro Matsuda (KOKUSAI ELECTRIC), Co-chair	July 23, 2019

Table 13 Index of Available Attachments#1

<i>Title</i>	<i>Title</i>
01-02_SEMI Standards Required Elements_August2018_E+J	04-03_6481_Ballot report template (Line Item) with Technical Change Rev1.5_r4
02-00_20181214_IC_Minutes_Final	05-01_JA_ICC_GEM300_TF_Report_2019_0417_R1.1
03-02_IC_KR_Liaison_April2019_v2	05-04_DDATF_Japan_20190417-Report_To_ICC
03-03_NA IC Liaison Report Apr 2019_v2	05-05_SEMI Stds JA FEIS TF Report_20190417
03-04_20190329_TW_I&C TC Liaison Report v1	07-01_20190417TraceabilityTC
03-05_SEMI CAST Overview 2019Apr25_Standards	
03-06_NA Liaison Report - ATE April 2019_v1	
03-07_SEMI Staff Report 2019_0409_v1	
04-01_6300B_Ballot report template with Technical Change Rev1.2_r4	
04-02_6377A_Ballot report (Line Item) with Technical Change Rev1.5_r4	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.